

67,200-447; TSMC 00-0890  
Serial Number 09/975,855

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**TO:** Commissioner for Patents  
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**FROM:** Tung & Associates  
838 West Long Lake Road - Suite 120  
Bloomfield Hills, MI 48302

TC 1700

**DATE:** 29 November 2003

**REF:** Applicant : Hsieh et al. Filing Date : 11 October 2001  
Serial No : 09/975,855 Att'y No. : 67,200-447  
Art Unit : 1756 Examiner : Saleha R Mohamedulla  
Title : Gap Forming Pattern Fracturing Method for Forming Optical  
Proximity Corrected Masking Layer

AMENDMENT AND RESPONSE TO OFFICE ACTION

Sir:

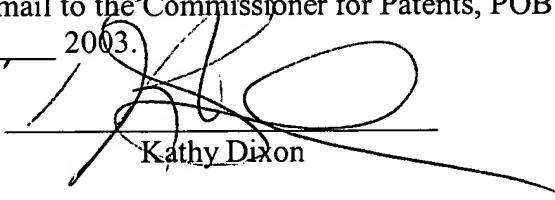
In response to an office action mailed on 10 October 2003, please consider the following amendments and remarks pertaining to the above referenced application.

Amendments to the specification begin on page 2 of this paper. Amendments to the claims are found within a Listing of the Claims that begins on page 3 of this paper. Amendments to the drawings begin on page 7 of this paper. Remarks begin on page 8 of this paper.

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being forwarded in an envelope with sufficient postage as first class mail to the Commissioner for Patents, POB 1450, Alexandria, VA 22313-1450 on Dec. 23, 2003.



Kathy Dixon